

# Gleb A Iankevich

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/3082302/publications.pdf>

Version: 2024-02-01

12  
papers

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1684188

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1474206

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g-index

12  
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12  
docs citations

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times ranked

56  
citing authors

#	ARTICLE	IF	CITATIONS
1	Silicon carbide dry etching technique for pressure sensors design. Journal of Manufacturing Processes, 2022, 73, 316-325.	5.9	4
2	Artificial synapses based on Josephson junctions with Fe nanoclusters in the amorphous Ge barrier. Journal of Applied Physics, 2022, 131, 073902.	2.5	7
3	OES diagnostics as a universal technique to control the Si etching structures profile in ICP. Scientific Reports, 2022, 12, 5287.	3.3	4
4	Deep Etching of LiNbO <sub>3</sub> Using Inductively Coupled Plasma in SF <sub>6</sub> -Based Gas Mixture. Journal of Microelectromechanical Systems, 2021, 30, 90-95.	2.5	5
5	Monocrystalline Quartz ICP Etching: Road to High-Temperature Dry Etching. Plasma Chemistry and Plasma Processing, 2020, 40, 423-431.	2.4	13
6	High-temperature etching of SiC in SF <sub>6</sub> /O <sub>2</sub> inductively coupled plasma. Scientific Reports, 2020, 10, 19977.	3.3	29
7	Magnetotransport Properties of Ferromagnetic Nanoparticles in a Semiconductor Matrix Studied by Precise Size-Selective Cluster Ion Beam Deposition. Nanomaterials, 2020, 10, 2192.	4.1	7
8	ICP etching of SiC with low surface roughness. Materials Today: Proceedings, 2020, 30, 512-515.	1.8	1
9	Corona discharge plasma application for the deposition of nanocomposite coatings. Materials Today: Proceedings, 2020, 30, 404-407.	1.8	4
10	Aerosol-Assisted Chemical Deposition of Nanocomposite Material in the "Iron-Carbon-Oxygen" System. Key Engineering Materials, 2019, 822, 320-326.	0.4	0
11	Registration of an ICP Plasma CV Dependences under Various Pressures in the Plasma-Chemical Deep Etching System. Key Engineering Materials, 2019, 822, 587-593.	0.4	0
12	The effect of a lithium niobate heating on the etching rate in SF <sub>6</sub> ICP plasma. Materials Research Express, 2019, 6, 046306.	1.6	12